

Abstract

5 An objective lens with magnetic and electrostatic focusing for an electron microscopy
system is provided whose at least partially conical outer shape allows orienting an object
to be imaged at a large angle range in respect of an electron beam, said objective lens
exhibiting, at the same time, good optical parameters. This is enabled by a specific
geometry of the lens elements. Furthermore, an examination for the simultaneous
10 imaging and processing of an object is proposed which comprises, besides an electron
microscopy system with the above-mentioned objective lens, also an ion beam processing
system and an object support.

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